

<b>Notice of References Cited</b>	Application/Control No. 10/644,116	Applicant(s)/Patent Under Reexamination BLACKWOOD ET AL.	
	Examiner DANIEL G. MARIAM	Art Unit 2624	Page 1 of 1

#### U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-4,680,635	07-1987	Khurana, Neeraj	348/79
*	B	US-4,755,874	07-1988	Esrig et al.	348/126
*	C	US-5,970,167	10-1999	Colvin, James Barry	382/149
*	D	US-6,716,683	04-2004	Bruce et al.	438/151
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

#### FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

#### NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Trigg "The infrared photoemission microscope as a tool for semiconductor device failure analysis", IEEE, pp. 21-26, 1997.
	V	Khiam, et al "A new fluorescent and photoemission microscope for submicron VLSI IC failure analysis", IEEE, pp. 27-32.
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.